## STN-ScarcH Do NOT Remove:

Uploading C:\Program Files\Stnexp\Queries\098346391-1.str

L1 STRUCTURE UPLOADED

=> que L1

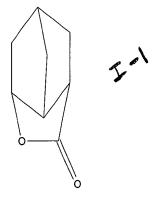
L2 QUE L1

=> d

L2 HAS NO ANSWERS

L1

STR



Structure attributes must be viewed using STN Express query preparation. L2 QUE ABB=ON PLU=ON L1

=> s 12 SAMPLE SEARCH INITIATED 13:29:11 FILE 'REGISTRY' SAMPLE SCREEN SEARCH COMPLETED - 5051 TO ITERATE

19.8% PROCESSED 1000 ITERATIONS INCOMPLETE SEARCH (SYSTEM LIMIT EXCEEDED) SEARCH TIME: 00.00.01

9 ANSWERS

FULL FILE PROJECTIONS: ONLINE \*\*COMPLETE\*\*

BATCH \*\*COMPLETE\*\*

PROJECTED ITERATIONS:

96761 TO 105279

PROJECTED ANSWERS: 505 TO 1313

L3 9 SEA SSS SAM L1

=> d 13

L3 ANSWER 1 OF 9 REGISTRY COPYRIGHT 2002 ACS

RN 460096-52-0 REGISTRY

CN INDEX NAME NOT YET ASSIGNED

MF (C18 H28 O2 . C14 H20 O3 . C12 H14 O4) x

CI PMS

PCT Polyacrylic

SR CA

LC STN Files: CAPLUS

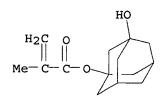
CM 1

CRN 460096-50-8 CMF C18 H28 O2

CRN 254900-07-7 CMF C12 H14 O4

CM 3

CRN 115372-36-6 CMF C14 H20 O3



## 1 REFERENCES IN FILE CAPLUS (1962 TO DATE)

=> FIL USPATFULL CAPLUS HCAPLUS COST IN U.S. DOLLARS

SINCE FILE

TOTAL

ENTRY

SESSION 2.17

FULL ESTIMATED COST

1.96

FILE 'USPATFULL' ENTERED AT 13:29:37 ON 10 OCT 2002 CA INDEXING COPYRIGHT (C) 2002 AMERICAN CHEMICAL SOCIETY (ACS)

FILE 'CAPLUS' ENTERED AT 13:29:37 ON 10 OCT 2002 USE IS SUBJECT TO THE TERMS OF YOUR STN CUSTOMER AGREEMENT. PLEASE SEE "HELP USAGETERMS" FOR DETAILS. COPYRIGHT (C) 2002 AMERICAN CHEMICAL SOCIETY (ACS)

FILE 'HCAPLUS' ENTERED AT 13:29:37 ON 10 OCT 2002 USE IS SUBJECT TO THE TERMS OF YOUR STN CUSTOMER AGREEMENT. PLEASE SEE "HELP USAGETERMS" FOR DETAILS. COPYRIGHT (C) 2002 AMERICAN CHEMICAL SOCIETY (ACS)

=> d his

```
(FILE 'HOME' ENTERED AT 13:28:23 ON 10 OCT 2002)
     FILE 'REGISTRY' ENTERED AT 13:28:51 ON 10 OCT 2002
L1
                STRUCTURE UPLOADED
L2
                QUE L1
Ь3
              9 S L2
     FILE 'USPATFULL, CAPLUS, HCAPLUS' ENTERED AT 13:29:37 ON 10 OCT 2002
=> s 13
L4
            22 L3
=> s 14 and (resist or photoresist)
            12 L4 AND (RESIST OR PHOTORESIST)
=> hide duplicates
HIDE IS NOT A RECOGNIZED COMMAND
The previous command name entered was not recognized by the system.
For a list of commands available to you in the current file, enter
"HELP COMMANDS" at an arrow prompt (=>).
=> duplicate
ENTER REMOVE, IDENTIFY, ONLY, OR (?):remove
ENTER L# LIST OR (END):15
DUPLICATE PREFERENCE IS 'USPATFULL, CAPLUS, HCAPLUS'
KEEP DUPLICATES FROM MORE THAN ONE FILE? Y/(N):n
PROCESSING COMPLETED FOR L5
              7 DUPLICATE REMOVE L5 (5 DUPLICATES REMOVED)
=> d l6 1-7 ibib abs hitstr
    ANSWER 1 OF 7 CAPLUS COPYRIGHT 2002 ACS
                                                       DUPLICATE 1
ACCESSION NUMBER:
                         2002:708833 CAPLUS
TITLE:
                         Chemical compounds for photoresists and
                         resin compositions for photoresists
INVENTOR (S):
                         Tsutsumi, Kiyoharu; Itokazu, Teruo
PATENT ASSIGNEE(S):
                         Daicel Chemical Industries, Ltd., Japan
SOURCE:
                         Jpn. Kokai Tokkyo Koho, 19 pp.
                         CODEN: JKXXAF
DOCUMENT TYPE:
                         Patent
LANGUAGE:
                         Japanese
FAMILY ACC. NUM. COUNT:
PATENT INFORMATION:
    PATENT NO.
                                           APPLICATION NO. DATE
                      KTND
                            DATE
                                           -----
                                           JP 2001-62435
     JP 2002265530
                      A2
                            20020918
                                                            20010306
AB
     The compds. are 2-(meth)acryloyloxy-tricyclo[7.4.0.03,8]tridecanes
     optionally having 2-hydrocarbyl (C1-10) substitutions. Thus,
     2-methacryloyloxy-2-methyltricyclo[7.4.0.03,8]tridecane and its copolymer
    with 5-methacryloyloxy-3-oxatricyclo[4.2.1.04,8]nonane-2-one were prepd.
IT
     460096-52-0P
     RL: IMF (Industrial manufacture); PREP (Preparation)
        ((meth)acryloyloxytricyclotridecanes and polymers for
        photoresists)
RN
     460096-52-0 CAPLUS
CN
     INDEX NAME NOT YET ASSIGNED
     CM
          1
     CRN
         460096-50-8
```

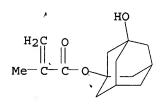
CMF

C18 H28 O2

CRN 254900-07-7 CMF C12 H14 O4

CM

CRN 115372-36-6 CMF C14 H20 O3



ANSWER 2 OF 7 CAPLUS COPYRIGHT 2002 ACS

2002:673049 CAPLUS

ACCESSION NUMBER: DOCUMENT NUMBER:

137:208381

TITLE:

Storage-stable chemically amplified UV positive

photoresist compositions with good

post-exposure stability for halftone exposure

INVENTOR(S):

Sato, Kenichiro; Kodama, Kunihiko PATENT ASSIGNEE(S): Fuji Photo Film Co., Ltd., Japan Jpn. Kokai Tokkyo Koho, 87 pp.

CODEN: JKXXAF

DOCUMENT TYPE:

Patent

LANGUAGE:

SOURCE:

Japanese

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

KIND DATE

PATENT NO. JP 2002251013 A2 20020906 APPLICATION NO. DATE

DUPLICATE 2

JP 2001-48880

20010223

GI

{

AB The compns. comprise (A) resins contg. alicyclic hydrocarbon groups and groups selected from I, II, III, and IV (R1b, R2b, R3b, R4b, R5b = H, alkyl, cycloalkyl, alkenyl), which increase their alkali soly. by acid decompn. and (B) .gtoreq.2 photoacid generators selected from triarylsulfonium salts, phenacylsulfonium salts, and non-arom. sulfonium salts.

IT 454470-90-7P

RL: IMF (Industrial manufacture); TEM (Technical or engineered material use); PREP (Preparation); USES (Uses)

(storage-stable chem. amplified UV pos. photoresists with good post-exposure stability for halftone exposure)

RN 454470-90-7 CAPLUS CN 2-Propenoic acid. 2

2-Propenoic acid, 2-methyl-, 2-ethyltricyclo[3.3.1.13,7]dec-2-yl ester, polymer with bicyclo[2.2.1]hept-2-ene, 2,5-furandione, hexahydro-5-methyl-2-oxo-3,5-methano-2H-cyclopenta[b]furan-6-yl 2-propenoate, hexahydro-6-methyl-2-oxo-3,5-methano-2H-cyclopenta[b]furan-6-yl 2-propenoate and hexahydro-6a-methyl-2-oxo-3,5-methano-2H-cyclopenta[b]furan-6-yl 2-propenoate (9CI) (CA INDEX NAME)

CM 1

CRN 392309-90-9 CMF C12 H14 O4

CM 2

CRN 392309-89-6 CMF C12 H14 O4

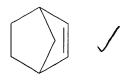
CRN 392309-87-4 CMF C12 H14 O4

CM 4

CRN 209982-56-9 CMF C16 H24 O2

CM 5

CRN 498-66-8 CMF C7 H10



CM 6

CRN 108-31-6 CMF C4 H2 O3



ANSWER 3 OF 7 CAPLUS COPYRIGHT 2002 ACS

DUPLICATE 3

ACCESSION NUMBER: DOCUMENT NUMBER:

2002:253088 CAPLUS

TITLE:

136:286596

Radiation sensitive resin composition

INVENTOR(S):

Miyaji, Masaaki; Nagai, Tomoki; Yada, Yuji; Numata, Jun; Nishimura, Yukio; Yamamoto, Masafumi; Ishii,

Hiroyuki; Kajita, Toru; Shimokawa, Tsutomu

PATENT ASSIGNEE(S):

SOURCE:

JSR Corporation, Japan Eur. Pat. Appl., 71 pp.

CODEN: EPXXDW

DOCUMENT TYPE:

Patent English

LANGUAGE:

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO. KIND				ND	DATE APPLICATION NO.			Ο.	DATE									
EP	1193	558		A2	2	2002	0403		:	EP :	200	1-12	2221	3	20010	917		
EP	1193	558		A:	3	2002	0814											
	R:	AT,	BE,	CH,	DE,	DK,	ES,	FR,	GB	, G	R,	ΙΤ,	LI,	LU,	NL,	SE,	MC,	PT,
		ΙE,	SI,	LT,	LV,	FI,	RO											
JP	2002	20260	)4	A2	2	2002	0719			JP :	200	0-40	130	2	20001	1228		
JP	2002	16274	<u> 1</u> 6	A2	2	2002	0607			JP :	200	1-28	3003	5	20010	914		
US	2002	05820	1	A:	l	2002	0516		1	US :	200	1-95	394	1	20010	918		
PRIORITY	APP	LN. I	NFO.	:				i	JP :	200	0-2	8268	39	Α	20000	918	_	
								i	JP :	200	0-4	013	)2	A	20001	1228		

GI

$$\begin{array}{c|c}
R^1 & & & \\
CH_2C & & & \\
\hline
CH_2C & & \\
\hline
OR^2 & & \\
\hline
II & & \\
\end{array}$$

A chem. amplified radiation sensitive resin compn. comprises a specific AΒ copolymer and a photoacid generator, wherein the copolymer contains the recurring unit I and/or II and CH2CR1(C:O)NR3R4 (R1 = H, Me; R2 = C4-10 tertiary alkyl; R3,4 = H, C1-12 alkyl, C6-15 arom., C1-12 alkoxyl, or R3 and R4 may form, in combination and together with the nitrogen atom with which the R3 and R4 groups bond, a C3-14 cyclic structure, provided that R3 and R4 are not a hydrogen atom at the same time). The compn. effectively responds to various radiations, exhibits excellent resoln. and pattern configuration and minimal iso-dense bias, and can form fine patterns at a high precision and in a stable manner.

IT 406198-73-0P

> RL: PRP (Properties); SPN (Synthetic preparation); TEM (Technical or engineered material use); PREP (Preparation); USES (Uses) (resin; radiation sensitive resin compn. for photoresist contg.)

RN406198-73-0 CAPLUS

CN 2-Propenoic acid, 2-methyl-, polymer with N,N-dimethyl-2-propenamide, 1-ethylcyclohexyl 2-methyl-2-propenoate and hexahydro-2-oxo-3,5-methano-2H- cyclopenta[b] furan-6-yl 2-methyl-2-propenoate (9CI) (CA INDEX NAME)

CM 1

CRN 274248-09-8 CMF C12 H20 O2

The control of the co

CM 2

CRN 254900-07-7 CMF C12 H14 O4

CM 3

CRN 2680-03-7 CMF C5 H9 N O

CM 4

CRN 79-41-4 CMF C4 H6 O2

$$\begin{array}{c} \text{CH}_2 \\ || \\ \text{Me-C-CO}_2 \text{H} \end{array}$$

L6 ANSWER 4 OF 7 USPATFULL

ACCESSION NUMBER:

2002:112468 USPATFULL

TITLE: INVENTOR(S): Radiation-sensitive resin composition Miyaji, Masaaki, Yokkaichi, JAPAN

Nagai, Tomoki, Yokkaichi, JAPAN

Yada, Yuji, Yokkaichi, JAPAN Numata, Jun, Yokkaichi, JAPAN Nishimura, Yukio, Yokkaichi, JAPAN Yamamoto, Masafumi, Yokkaichi, JAPAN Ishii, Hiroyuki, Yokkaichi, JAPAN Kajita, Toru, Yokkaichi, JAPAN Shimokawa, Tsutomu, Suzuka, JAPAN

NUMBER KIND DATE SIBOR US 2002058201 A1 20020516 US 2001-953941 A1 20010918 (9) Q | F| D |

20001228

DOCUMENT TYPE: Utility
FILE SEGMENT: APPLICATION

LEGAL REPRESENTATIVE: Supervisor, Patent Prosecution Services, PIPER MARBURY

RUDNICK & WOLFE LLP, 1200 Nineteenth Street, N.W.,

Washington, DC, 20036-2412

JP 2000-401302

NUMBER OF CLAIMS: 14
EXEMPLARY CLAIM: 1
LINE COUNT: 3791

PATENT INFORMATION:

APPLICATION INFO.:

PRIORITY INFORMATION:

CAS INDEXING IS AVAILABLE FOR THIS PATENT.

AB A chemically amplified radiation-sensitive resin composition comprising a specific copolymer and a photoacid generator, wherein the copolymer contains the following recurring unit (1) and/or the recurring unit (2), and the recurring unit (3-1), ##STR1##

wherein R.sup.1 is a hydrogen or methyl, R.sup.2 is a C.sub.4-10 tertiary alkyl, R.sup.3 and R.sup.4 are a hydrogen, C.sub.1-12 alkyl, C.sub.6-15 aromatic, C.sub.1-12 alkoxyl, or R.sup.3 and R.sup.4 may form, in combination and together with the nitrogen atom with which the R.sup.3 and R.sup.4 groups bond, a C.sub.3-15 cyclic structure, provided that R.sup.3 and R.sup.4 are not a hydrogen atom at the same time. The composition effectively responds to various radiations, exhibits excellent resolution and pattern configuration and minimal iso-dense bias, and can form fine patterns at a high precision and in a stable manner.

CAS INDEXING IS AVAILABLE FOR THIS PATENT.

IT 406198-73-0P

(resin; radiation sensitive resin compn. for photoresist contg.)

RN 406198-73-0 USPATFULL

CN 2-Propenoic acid, 2-methyl-, polymer with N,N-dimethyl-2-propenamide, 1-ethylcyclohexyl 2-methyl-2-propenoate and hexahydro-2-oxo-3,5-methano-2H-cyclopenta[b]furan-6-yl 2-methyl-2-propenoate (9CI) (CA INDEX NAME)

CM 1

CRN 274248-09-8 CMF C12 H20 O2

CRN 254900-07-7 CMF C12 H14 O4

3 CM

CRN 2680-03-7 CMF C5 H9 N O

$$\begin{array}{c} \text{O} \\ || \\ \text{Me}_2 \text{N-C-CH-} \end{array} \text{CH}_2$$

CM 4

CRN 79-41-4 CMF C4 H6 O2

ANSWER 5 OF 7 CAPLUS COPYRIGHT 2002 ACS

2001:280498 CAPLUS

ACCESSION NUMBER: DOCUMENT NUMBER:

134:318676

TITLE:

SOURCE:

Positive-working far-UV-sensitive photoresist

composition containing acid-sensitive resin having

DUPLICATE 4

lactone group

INVENTOR (S):

Aogo, Toshiaki; Sato, Kenichiro; Kodama, Kunihiko

Fuji Photo Film Co., Ltd., Japan PATENT ASSIGNEE(S): Jpn. Kokai Tokkyo Koho, 58 pp.

CODEN: JKXXAF

DOCUMENT TYPE:

Patent

LANGUAGE:

Japanese

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO. KIND DATE APPLICATION NO. DATE ----------------JP 2001109154 A2 20010420 JP 1999-285762 19991006 AB The title compn. contains a photoacid generator and a resin, which increases the soly. towards an alkali developer reacting with an acid, of a lactone repeating group. The compn., which contains the acid-sensitive resin having lactone group, shows the high sensitivity and provides the

pattern of the high resoln., the good contact with substrate, and little edge roughness.

IT 335163-68-3P, 2-Methyl-2-adamantylmethacrylate-

Bicyclo[2.2.1]heptane-2-carboxylic acid,7-hydroxy-,.gamma.-lactone,

5-exo-methacrylate ester copolymer

RL: SPN (Synthetic preparation); TEM (Technical or engineered material use); PREP (Preparation); USES (Uses)

(pos.-working far-UV-sensitive photoresist compn.)

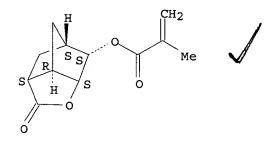
RN 335163-68-3 CAPLUS

CN 2-Propenoic acid, 2-methyl-, (3S,3aR,5S,6S,6aS)-hexahydro-2-oxo-3,5-methano-2H-cyclopenta[b] furan-6-yl ester, polymer with 2-methyltricyclo[3.3.1.13,7]dec-2-yl 2-methyl-2-propenoate (9CI) (CA INDEX NAME)

CM 1

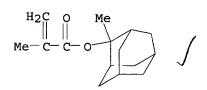
CRN 335163-67-2 CMF C12 H14 O4

Relative stereochemistry.



CM 2

CRN 177080-67-0 CMF C15 H22 O2



L6 ANSWER 6 OF 7 CAPLUS COPYRIGHT 2002 ACS DUPLICATE 5

ACCESSION NUMBER:

2001:747251 CAPLUS

DOCUMENT NUMBER:

135:296190

TITLE:

Chemically amplified positive resist

INVENTOR(S):

composition

Uetani, Yasunori; Yamada, Airi; Miya, Yoshiko; Takata,
Yoshiyuki

PATENT ASSIGNEE(S):

Sumitomo Chemical Company, Limited, Japan

SOURCE: Eur. Pat. Appl., 18 pp.

CODEN: EPXXDW

DOCUMENT TYPE:

Patent

LANGUAGE:

English

FAMILY ACC. NUM. COUNT: 1

PATENT INFORMATION:

PATENT NO.

KIND DATE

APPLICATION NO. DATE

EP 1143299 A1 20011010 EP 2001-107747 20010402 AT, BE, CH, DE, DK, ES, FR, GB, GR, IT, LI, LU, NL, SE, MC, IE, SI, LT, LV, FI, RO CN 1316675 20010402 20011010 CN 2001-110230 20011122 US 2001044070 US 2001-824227 20010403 20021009 JP 2002296783 JP 2001-104302 20010403 PRIORITY APPLN. INFO.: JP 2000-101868 20000404 JP 2000-133328 Α 20000502 JP 2000-209505 A 20000711 JP 2001-14261 A 20010123 GI

\* STRUCTURE DIAGRAM TOO LARGE FOR DISPLAY - AVAILABLE VIA OFFLINE PRINT \*

AB A chem. amplification type pos. resist compn. comprises an acid generating agent and a resin having polymeric units (A), (B) and (C). The polymeric unit (A) is an alicyclic lactone selected from polymeric units I and II (R1,2 = H, Me; and n = 1-3). The polymeric unit (B) is selected 3-hydroxy-1-adamantyl (meth)acrylate represented by III, IV (R3 = H, methyl; R4 = H, hydroxyl; R5,6 = H, C1-3 alkyl or hydroxyalkyl, etc.) and a unit derived from unsatd. dicarboxylic acid anhydride selected from maleic anhydride and itaconic anhydride and a polymeric unit of (.alpha.). beta.-(meth)acryloyloxy-.gamma. -butyrolactone represented by V (R7 = H, Me). The polymeric unit (C) is the one which becomes alkali-sol. by cleavage of a part of groups by the action of an acid. The pos. resist compn. of this invention is excellent in balance of properties such as resoln., profile, sensitivity, dry etching resistance, adhesion, and the like.

IT 364736-27-6P

RN 364736-27-6 CAPLUS

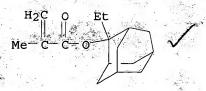
CN 2-Propenoic acid, 2-methyl-, 2-ethyltricyclo[3.3.1.13,7]dec-2-yl ester, polymer with hexahydro-2-oxo-3,5-methano-2H-cyclopenta[b]furan-6-yl 2-methyl-2-propenoate, 3-hydroxytricyclo[3.3.1.13,7]dec-1-yl 2-methyl-2-propenoate and tetrahydro-2-oxo-3-furanyl 2-methyl-2-propenoate (9CI) (CA INDEX NAME)

CM 1

CRN 254900-07-7 CMF C12 H14 O4

CM 2

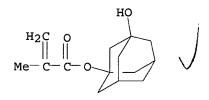
CRN 209982-56-9 CMF C16 H24 O2



CRN 195000-66-9 CMF C8 H10 O4

CM 4

CRN 115372-36-6 CMF C14 H20 O3



REFERENCE COUNT:

THERE ARE 2 CITED REFERENCES AVAILABLE FOR THIS RECORD. ALL CITATIONS AVAILABLE IN THE RE FORMAT

L6 ANSWER 7 OF 7 USPATFULL

ACCESSION NUMBER: 2001:212076 USPATFULL

TITLE: Chemically amplified positive resist

composition

INVENTOR(S): Uetani, Yasunori, Osaka, Japan

2

Yamada, Airi, Osaka, Japan Miya, Yoshiko, Muko-shi, Japan Takata, Yoshiyuki, Osaka, Japan

	NUMBER	KIND	DATE	
PATENT INFORMATION:	US 2001044070	A1	20011122	
APPLICATION INFO.:	US 2001-824227	A1	20010403	(9)

	NUMBER	DATE
		<del></del>
PRIORITY INFORMATION:	JP 2000-101868	20000404
	JP 2000-133328	20000502
	JP 2000-209505	20000711
DOCUMENT TYPE:	Utility	

DOCUMENT TYPE: Utility
FILE SEGMENT: APPLICATION

LEGAL REPRESENTATIVE: BIRCH STEWART KOLASCH & BIRCH, PO BOX 747, FALLS

CHURCH, VA, 22040-0747

NUMBER OF CLAIMS:

7

EXEMPLARY CLAIM:

LINE COUNT: 894

CAS INDEXING IS AVAILABLE FOR THIS PATENT.

A chemical amplification type positive resist composition excellent in balance of properties such as resolution, profile, sensitivity, dry etching resistance, adhesion and the like which comprises a resin which has the following polymeric units (A), (B) and (C); and an acid generating agent.

- (A): At least one polymeric unit of an alicyclic lactcone selected from polymeric units represented by the following formulae (Ia) and (Ib): ##STR1##
- (B): At least one polymeric unit selected from a polymeric unit of 3-hydroxy-1-adamantyl (meth)acrylate represented by the following formula (II), a polymeric unit of a combination of a unit represented by the following formula (III) and a unit derived from unsaturated dicarboxylic acid anhydride selected from maleic anhydride and itaconic anhydride and a polymeric unit of (.alpha.).beta.-(meth)acryloyy-.gamma.-butyrolactone represented by the following formula (IV): ##STR2##
- (C) A polymeric unit which becomes alkali-soluble by cleavage of a part of groups by the action of an acid.

CAS INDEXING IS AVAILABLE FOR THIS PATENT.

IT 364736-27-6P, 2-Ethyl-2-adamantyl methacrylate-3-hydroxy-1adamantyl methacrylate-5-methacryloyloxy-2,6-norbornanecarbolactone-.alpha.-methacryloyloxy-.gamma.-butyrolactone copolymer

(chem. amplified pos. resist compn. contq.)

RN364736-27-6 USPATFULL

CN 2-Propenoic acid, 2-methyl-, 2-ethyltricyclo[3.3.1.13,7]dec-2-vl ester, polymer with hexahydro-2-oxo-3,5-methano-2H-cyclopenta[b]furan-6-yl 2-methyl-2-propenoate, 3-hydroxytricyclo[3.3.1.13,7]dec-1-yl 2-methyl-2-propenoate and tetrahydro-2-oxo-3-furanyl 2-methyl-2-propenoate (9CI) (CA INDEX NAME)

CM 1

CRN 254900-07-7 CMF C12 H14 O4

CM 2

CRN 209982-56-9 CMF C16 H24 O2

CRN 195000-66-9 CMF C8 H10 O4

The state of the s

CM 4

CRN 115372-36-6 CMF C14 H20 O3

=>

USPATFULL L11 ANSWER 1 OF 3

ACCESSION NUMBER: 2002:16787 USPATFULL

TITLE: Positive photoresist composition INVENTOR (S): Sato, Kenichiro, Shizuoka, JAPAN Aoai, Toshiaki, Shizuoka, JAPAN

1/24/0001 NUMBER DATE KIND ATENT INFORMATION: US 2002009666 20020124 A1 APPLICATION INFO.: US 2001-834639 20010416 Α1

NUMBER DATE

\_\_\_\_\_

PRIORITY INFORMATION: JP 2000-115497 20000417 JP 2000-215574 20000717

JP 2000-231670 20000731

DOCUMENT TYPE: Utility FILE SEGMENT: APPLICATION

LEGAL REPRESENTATIVE: SUGHRUE, MION, ZINN, MACPEAK & SEAS, PLLC, 2100 Pennsylvania Avenue, N.W., Washington, DC, 20037

NUMBER OF CLAIMS: EXEMPLARY CLAIM: 1 LINE COUNT: 1642

CAS INDEXING IS AVAILABLE FOR THIS PATENT.

Provided is a positive photoresist composition comprising a resin which contains specific repeating units and whose dissolving rate toward an alkaline developing solution is increased by the action of an acid and a compound which generates an acid upon irradiation with an actinic ray or a radiation.

CAS INDEXING IS AVAILABLE FOR THIS PATENT.

392309-94-3P

(acid-decomposable resin; pos. photoresist compn. contq.)

RN 392309-94-3 USPATFULL

CN2-Propenoic acid, 7-methyl-5-oxo-4-oxatricyclo[4.3.0.03,8]non-7-yl ester, polymer with bicyclo[2.2.1]hept-2-ene, 2,5-furandione, 1-methyl-1-tricyclo[3.3.1.13,7]dec-1-ylethyl 2-propenoate and octahydro-1,4,4,6-tetramethyl-1H-5,8a-methanoazulen-6-yl 2-propenoate (9CI) (CA INDEX NAME)

CM 1

CRN 392309-93-2 CMF C12 H14 O4

H2C== CH-

CM

CRN 313698-62-3 CMF C18 H28 O2

 $\mathsf{CM}$ 

CRN 300833-10-7 CMF C16 H24 O2

CM

CRN 498-66-8 CMF C7 H10



CM

CRN 108-31-6 CMF C4 H2 O3

L11 ANSWER 2 OF 3 CAPLUS COPYRIGHT 2002 ACS

ACCESSION NUMBER:

2002:72739 CAPLUS

DOCUMENT NUMBER:

136:142610

TITLE:

Positive photoresist composition Sato, Kenichiro; Aoai, Toshiaki

1. 19 VO

INVENTOR(S): PATENT ASSIGNEE(S):

Japan

SOURCE:

U.S. Pat. Appl. Publ., 49 pp.

CODEN: USXXCO

DOCUMENT TYPE:

Patent

LANGUAGE:

English

2

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO. DATE
US 2002009666	A1	20020124	US 2001-834639 / 20010416
JP 2001296661	A2	20011026	JP 2000 11549 20000417
JP 2002031890	A2	20020131	JP 2000-215574 20000717
JP 2002040662	A2	20020206	JP 2000-231670 20000731
PRIORITY APPLN. INFO.	:		JP 2000-115497 A 20000417
			JP 2000-215574 A 20000717
			JP 2000-231670 A 20000731

AB Provided is a pos. photoresist compn. comprising a resin which contains specific repeating units and whose dissolving rate toward an alk. developing soln. is increased by the action of an acid and a compd. which generates an acid upon irradn. with an actinic ray or a radiation. The present invention relates to pos. photoresist compn. used in an ultramicrolithog. process, e.g., for the prodn. of VLSI and high capacity microchips processes.

IT 392309-94-3P

RN 392309-94-3 CAPLUS

CN 2-Propenoic acid, 7-methyl-5-oxo-4-oxatricyclo[4.3.0.03,8]non-7-yl ester, polymer with bicyclo[2.2.1]hept-2-ene, 2,5-furandione, 1-methyl-1-tricyclo[3.3.1.13,7]dec-1-ylethyl 2-propenoate and octahydro-1,4,4,6-tetramethyl-1H-5,8a-methanoazulen-6-yl 2-propenoate (9CI) (CA INDEX NAME)

CM 1

CRN 392309-93-2 CMF C12 H14 O4

CM 2

CRN 313698-62-3 CMF C18 H28 O2

CM 3

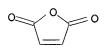
CRN 300833-10-7

CRN 498-66-8 CMF C7 H10



CM 5

CRN 108-31-6 CMF C4 H2 O3



L11 ANSWER 3 OF 3 HCAPLUS COPYRIGHT 2002 ACS

ACCESSION NUMBER:

2002:72739 HCAPLUS

DOCUMENT NUMBER:

136:142610

TITLE:

Positive photoresist composition Sato, Kenichiro; Aoai, Toshiaki

INVENTOR(S):
PATENT ASSIGNEE(S):

Japan

SOURCE:

U.S. Pat. Appl. Publ., 49 pp.

CODEN: USXXCO

DOCUMENT TYPE:

Patent English

LANGUAGE:

FAMILY ACC. NUM. COUNT: 2

PATENT INFORMATION:

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
			}	
US 2002009666	A1	20020124	US 2001-(834639/	20010416
JP 2001296661	A2	20011026	JP 2000-115497	20000417
JP 2002031890	A2	20020131	JP 2000-215574	20000717
JP 2002040662	A2	20020206	JP 2000-231670	20000731
PRIORITY APPLN. INFO.	:		JP 2000-115497 A	20000417
			JP 2000-215574 A	20000717
			JP 2000-231670 A	20000731

AB Provided is a pos. photoresist compn. comprising a resin which contains specific repeating units and whose dissolving rate toward an alk. developing soln. is increased by the action of an acid and a compd. which

generates an acid upon irradn. with an actinic ray or a radiation. The present invention relates to pos. photoresist compn. used in an ultramicrolithog. process, e.g., for the prodn. of VLSI and high capacity microchips processes.

100

IT 392309-94-3P

RL: SPN (Synthetic preparation); TEM (Technical or engineered material use); PREP (Preparation); USES (Uses)

(acid-decomposable resin; pos. photoresist compn. contg.)

RN 392309-94-3 HCAPLUS

CN 2-Propenoic acid, 7-methyl-5-oxo-4-oxatricyclo[4.3.0.03,8]non-7-yl ester, polymer with bicyclo[2.2.1]hept-2-ene, 2,5-furandione, 1-methyl-1-tricyclo[3.3.1.13,7]dec-1-ylethyl 2-propenoate and octahydro-1,4,4,6-tetramethyl-1H-5,8a-methanoazulen-6-yl 2-propenoate (9CI) (CA INDEX NAME)

CM 1

CRN 392309-93-2 CMF C12 H14 O4

CM 2

CRN 313698-62-3 CMF C18 H28 O2

$$H_2C = CH - C - O$$
 $Me$ 
 $Me$ 
 $Me$ 
 $Me$ 
 $Me$ 

CM 3

CRN 300833-10-7 CMF C16 H24 O2

CRN 498-66-8 CMF C7 H10



CM !

CRN 108-31-6 CMF C4 H2 O3

## => d l17 1 ibib abs hitstr

L17 ANSWER 1 OF 1 HCAPLUS COPYRIGHT 2002 ACS

KIND

ACCESSION NUMBER:

2002:708833 HCAPLUS

TITLE:

Chemical compounds for photoresists and

resin compositions for photoresists

INVENTOR(S):

Tsutsumi, Kiyoharu; Itokazu, Teruo

PATENT ASSIGNEE(S):

Daicel Chemical Industries, Ltd., Japan

SOURCE:

Jpn. Kokai Tokkyo Koho, 19 pp.

CODEN: JKXXAF

DOCUMENT TYPE:

Patent

LANGUAGE:

Japanese

FAMILY ACC. NUM. COUNT:

PATENT INFORMATION:

PATENT NO.

APPLICATION NO.

DATE

-----JP 2002265530

DATE A2 20020918

JP 2001-62435

-----20010306

AΒ The compds. are 2-(meth)acryloyloxy-tricyclo[7.4.0.03,8]tridecanes

optionally having 2-hydrocarbyl (C1-10) substitutions. Thus, 2-methacryloyloxy-2-methyltricyclo[7.4.0.03,8]tridecane and its copolymer with 5-methacryloyloxy-3-oxatricyclo[4.2.1.04,8]nonane-2-one were prepd.

IT 460096-52-0P

RL: IMF (Industrial manufacture); PREP (Preparation) ((meth)acryloyloxytricyclotridecanes and polymers for photoresists)

460096-52-0 HCAPLUS RN

CN INDEX NAME NOT YET ASSIGNED

> CM 1

CRN 460096-50-8 CMF C18 H28 O2

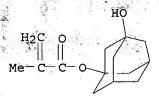
CH<sub>2</sub> C-Me

> CM 2

CRN 254900-07-7 CMF C12 H14 O4

CH<sub>2</sub> - C-- Me

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L24 ANSWER 1 OF 4 CAPLUS COPYRIGHT 2002 ACS DUPLICATE 1

ACCESSION NUMBER: 1996:296125 CAPLUS

DOCUMENT NUMBER: 125:86434

TITLE: Cycloadditions of 6H-1,3,4-oxadiazin-6-ones

> (4,5-diaza-.alpha.-pyrones). Part 15. Reactions of 6H-1,3,4-oxadiazin-6-ones with norbornadiene. A new

route to 3,6-disubstituted .alpha.-pyrones

AUTHOR (S):

Christl, Manfred; Bodenschatz, Gabriele; Fenineis,

Erich; Hegmann, Joachim; Huettner, Gerhard;

Mertelmeyer, Stefan; Schaetzlein, Klaus

CORPORATE SOURCE: Institut Organische Chemie, Universitaet Wuerzburg,

Wuerzburg, D-97074, Germany

Liebigs Annalen (1996), (5), 853-861 SOURCE:

CODEN: LANAEM; ISSN: 0947-3440

PUBLISHER: VCH

DOCUMENT TYPE: Journal LANGUAGE: English

CASREACT 125:86434 OTHER SOURCE(S):

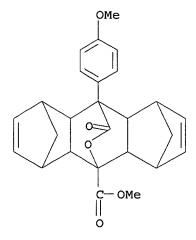
AB The oxadiazinones I (R = Me, Ph, 4-C6H4OMe, 4-C6H4NO2, CHMe2; R1 = CO2Me, Ph, 4-C6H4NO2, 4-C6H4Br, Me) were converted into the .alpha.-pyrones II upon reaction with norbornadiene. For this purpose, solns. of the substrates were treated with BF3.Et2O or F3CCO2H. The smooth formation of .alpha.-pyrones was also obsd. when a .gamma.-oxo ketene, initially generated by heating a soln. of the substrates in the absence of BF3.EtO2 was allowed to react with the Lewis acid. Without acid, only II (R =4-C6H4NO2, R1 = Ph) was obtained free from further compds., whereas in the other cases enol lactones and 1:2 products were formed addnl. Oxadiazinone I (R = Ph, R1 = Me) gave enol lactone III in the noncatalyzed reaction.

## IT 178413-65-5P

RL: SPN (Synthetic preparation); PREP (Preparation) (prepn. of .alpha.-pyrones by Diels-Alder reaction of oxadiazinones with norbornadiene)

RN 178413-65-5 CAPLUS

10,9-(Epoxymethano)-1,4:5,8-dimethanoanthracene-10(1H)-carboxylic acid, CN 4,4a,5,8,8a,9,9a,10a-octahydro-9-(4-methoxyphenyl)-12-oxo-, methyl ester, (1.alpha.,4.alpha.,4a.beta.,5.alpha.,8.alpha.,8a.beta.,9.alpha.,9a.beta.,1 0.alpha.,10a.beta.) - (9CI) (CA INDEX NAME)



L24 ANSWER 2 OF 4 CAPLUS COPYRIGHT 2002 ACS DUPLICATE 2

ACCESSION NUMBER:

1980:214496 CAPLUS

DOCUMENT NUMBER:

92:214496

TITLE:

Hydrochlorination and lactonization of

3-cyclohexenecarboxylic acid. II. Reactions of

1-methyl- and 1,2-, 1,3-, 1,4-, and

1,5-dimethyl-3-cyclohexenecarboxylic acids

AUTHOR (S):

Ismailov, A. G.; Rustamov, M. A.; Akhmedov, A. A. Azerb. Politekh. Inst., Baku, USSR

CORPORATE SOURCE: SOURCE:

Zh. Org. Khim. (1980), 16(1), 68-73

CODEN: ZORKAE; ISSN: 0514-7492

DOCUMENT TYPE:

Journal

LANGUAGE:

Russian

AB The regiochem. and stereochem. of the title reactions were examd. The conformation of the starting material influenced the product compn.

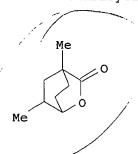
IT 73683-62-2P

RL: SPN (Synthetic preparation); PREP (Preparation)

(prepn. of)

RN 73683-62-2 CAPLUS

CN 2-Oxabicyclo[2.2.2]octan-3-one, 4,6-dimethyl- (9CI) (CA INDEX NAME)



L24\_ANSWER 3 OF 4 CAPLUS COPYRIGHT 2002 ACS DUPLICATE 3

ACCESSION NUMBER:

1977:484712 CAPLUS

DOCUMENT NUMBER:

87:84712

TITLE:

o-Quinonoid compounds. Part 12. Diels-Alder

additions to 1,3-dimethylcyclopenta[l]phenanthren-2-

one

AUTHOR (S):

Jones, David W.

CORPORATE SOURCE:

Dep. Org. Chem., Univ. Leeds, Leeds, Engl.

SOURCE:

J. Chem. Soc., Perkin Trans. 1 (1977), (9), 980-7

CODEN: JCPRB4

DOCUMENT TYPE:

Journal

LANGUAGE:

English

GI

Trapping expts. with N-phenylmaleimide, 1-phenyltriazoline-2,5-dione, and cyclopentadiene showed that the Diels-Alder dimer I (R = Me) of 1,3-dimethylcyclopenta[l]phenanthren-2-one (II; R = Me) is in rapid equil. with II (R = Me) at 20.degree. but no color accompanied dimer dissocn. Endo addn. of nonconjugated dienophiles is more important for II (R = Me) than for 2,5-dimethyl-3,4-diphenylcyclopentadienone (III) supporting the view that steric effects assocd. with noncoplanar Ph groups in III impede endo addn. Thermolysis or photolysis of II (R = Me) gave the formal [4 + 4].pi. dimer IV. II (R = Et) also exists as the dissocg. [4 + 2].pi. dimer I (R = Et) but II (R = Me2CH) is a sterically stabilized monomer which shows the same reactivity towards dienophiles as I (R = Me). The NMR spectra of I (R = Me, Et) are rationalized in terms of a Cope rearrangement.

IT 63902-29-4P

RN 63902-29-4 CAPLUS

CN 1,4-Ethano-1H-2-benzopyran-9-carboxylic acid, 3,4-dihydro-9-methyl-3-oxo-, methyl ester, (1.alpha.,4.alpha.,9S\*)- (9CI) (CA INDEX NAME)

Relative stereochemistry.

ACCESSION NUMBER:

1968:114143 CAPLUS

DOCUMENT NUMBER:

68:114143

TITLE:

Highly condensed polycyclic systems. I.

Tetra-cyclo[6.4.0.04,12.05.9]dodec-10-enes

AUTHOR (S):

Akhtar, I. A.; Fray, Gordon I.; Yarrow, J. M.

CORPORATE SOURCE:

Univ. Bristol, Bristol, Engl.

SOURCE:

J. Chem. Soc. C (1968), (7), 812-15

CODEN: JSOOAX

DOCUMENT TYPE:

Journal

English

LANGUAGE:

GI For diagram(s), see printed CA Issue.

AΒ Generation of the bicyclo[6.4.0]dodeca-4,9,11-triene system from cis, cis-cycloocta-1,5-diene, using tetracyclone, 1,2,3,4-tetrachloro-5,5-

dimethoxycyclopentadiene, or .alpha.-pyrone, is followed by an intramol.

Diels-Alder reaction and results in the formation of

tetracyclo[6.4.0.04,12.05,9]dodec-10-enes (I).

IT 18326-48-2P

RL: SPN (Synthetic preparation); PREP (Preparation)

(prepn. of)

18326~48-2 CAPLUS RN

4,3,7-[1] Propanyl [3] ylidenecyclopenta [b] pyran-7a (2H) -carboxylic acid, CN

3-chlorohexahydro-2-oxo-, methyl ester (8CI) (CA INDEX NAME)